



1639

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 09/763,914  
Applicant : STAHLER et al.  
Filed : May 11, 2001  
TC/A.U. : 1639  
Examiner : Padmashri Ponnaluri  
  
Docket No. : 2923-438  
Customer No. : 06449  
Confirmation No. : 3624

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

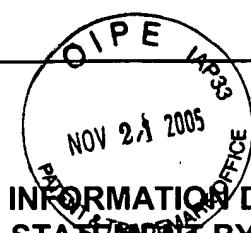
Director of the United States Patent  
and Trademark Office  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Dear Sir:

Under the provisions of 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicant submits herewith information that the Office may wish to consider in examination of the subject application. Materials submitted for consideration are listed on the attached form PTO-1449.

Applicants believe that no fee is due for this submission, however, if the Office deems a fee necessary, the Office is authorized to charge our deposit account number 02-2135.

RESPECTFULLY SUBMITTED,					
NAME AND REG. NUMBER	Martha Cassidy Reg. No. 44,066				
SIGNATURE			DATE	November 21, 2005	
Address	Rothwell, Figg, Ernst & Manbeck 1425 K Street, N.W., Suite 800				
City	Washington	State	D.C.	Zip Code	20005
Country	U.S.A.	Telephone	202-783-6040	Fax	202-783-6031



**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

				Complete if Known
Application Number				09/763,914
Filing Date				May 11, 2001
First Named Inventor				STAHLER et al.
Group Art Unit				1639
Examiner Name				Padmashri Ponnaluri
Confirmation No.				3624
Sheet		1	of	1
				Attorney Docket Number
				2923-438

**NON PATENT LITERATURE DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>
	R	Berstch et al., "Study of the Spatial Resolution of a New 3D Microfabrication Process: the Microstereolithography Using a Dynamic Mask-Generator Technique," <i>Journal of Photochemistry and Photobiology A: Chemistry</i> , 107:275-281, 1997.	
	S	Davidson Mark, "A Microlens Direct-Write Concept for Lithography," <i>SPIE</i> , 3048:346-355.	
	T	Hoheisel, J.D., "Oligomer-Chip Technology," <i>Trends in Biotechnology</i> , 15(11):465-469, 1997.	
	U	Singh-Gasson et al., "Maskless Fabrication of Light-Directed Oligonucleotide Microarrays Using a Digital Micromirror Array," <i>Nature Biotechnology</i> , 17:974-978, 1999.	
	V	Retrieved from the Internet: "Digital Optical Chemistry System," <a href="http://innovation.swmed.edu/research/instrumentation/higher_pages">http://innovation.swmed.edu/research/instrumentation/higher_pages</a>	
Examiner Signature		Date Considered	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup>Unique citation designation number. <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.